

**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER 1756**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masaaki KURIHARA et al.

Group Art Unit: 1756

Application No.: 10/614,345

Examiner: J. RUGGLES

Filed: July 8, 2003

Docket No.: 123770

For: PHASE MASK FOR FORMING DIFFRACTION GRATING, METHOD OF  
FABRICATING PHASE MASK AND METHOD OF FORMING DIFFRACTION  
GRATING

**AMENDMENT AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the May 30, 2006, Office Action, please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**